MOOV

Form System Audit

Centura Configurator

Manufacturer: Applied Materials
Centura Type: Etch
Serial Number:
Wafer Size: 200mm

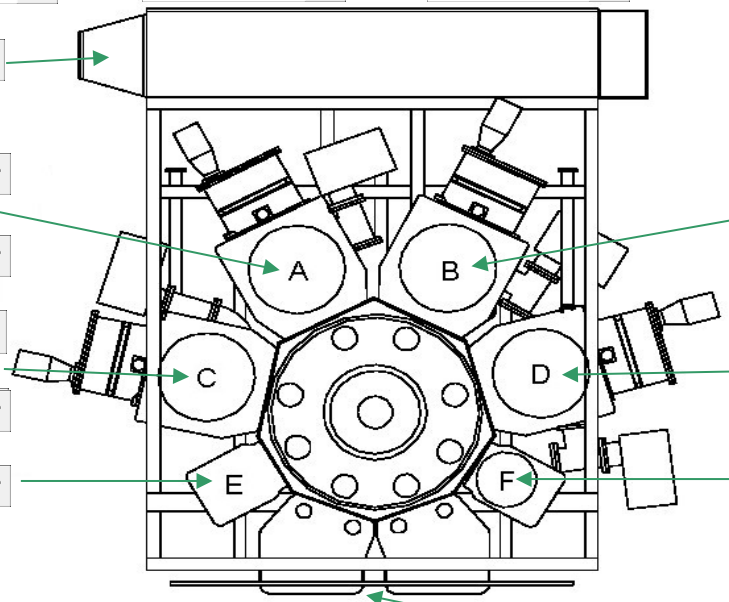
Mainbody: Type 1
Vinatge: 1997
Number of Chambers: 4
Condition: Complete

Deinstalled: Yes
Last Production: 2018

Centura Diagram

Gas Panel Facilities: Top Feed Multi-Line
Gas Panel Type: Seriplex
Liquid Source: none
Gas Lines:
System Power: 208VAC 250A

Gas Panel Exhaust: Top Feed
Mainframe: Phase I



Chamber A: DPS
Process A: Poly
Chamber B: Uni-body etch
Process B:
Chamber C: MkII
Process C:
Chamber D: DPS
Process D: Trench
Chamber E: Orienter
Chamber F: Orienter

Loadlock Pump Type: Edwards
Loadlock Pump Configuration: Ih80
Loadlock Slit Valves:
Heat Exchanger 1: Neslab
Heat Exchanger 2: Neslab
Heat Exchanger 3: Neslab
VME Rack: *System Controller
Hard Drive: *Hard Disk Drive

Robot Blade: Metal
Robot Type: HP
Wafer Size / Type: 200mm Notch
Fab Installation: TTW
Loadlock Type: Narrow Body w/o Tilt Out
Software Revision:
System Cabling:
Chase CRT:
Subfab CRT:
OTF: NO

System Notes:

Chamber A Information

Chamber Type	Chamber Process	Susceptor /Pedestal	Process Kit Type
DPS	Poly	Electostatic Chuck	
Manometer Config	**Lid Type**	**Wall Cooling**	**Chamber Pump**
Dual	DPS Poly		Edwards
Manometer 1	**Throttle Valve**	**Heater / Cathode Cooling**	**Pump Configuration**
.1 Torr	DPS Poly		Ih80
Manometer 2	**Source Generator**	**Endpoint System**	**Turbo Pump**
10 Torr	AE RF-20RWC	YES	Osaka TG2003M
Slit Valve O-Ring	**Bias Generator**	**Enpoint Software Rev.**	**Heated Valve Stack**
	ENI 12 B-03		NO
Chamber O-Rings	**RF Match**	**Chamber Clamps**	
	DPS bias	NO	

Chamber A Gases:

	MFC Size	Gas Name	MFC Type	Gas Stick Configuration
Gas 1	100 sccm	N2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 2	50 sccm	CHF3	Unit 1660 Press Buffered, Card Edg	Standard
Gas 3	*MFC Size	C4F8	Unit 1660 Press Buffered, Card Edg	Standard
Gas 4	*MFC Size	O2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 5	200 sccm	Ar	Unit 1660 Press Buffered, Card Edg	Standard
Gas 6	*MFC Size	BCl3	Unit 1660 Press Buffered, Card Edg	Standard
Gas 7	*MFC Size	CF4	Unit 1660 Press Buffered, Card Edg	Standard
Gas 8	*MFC Size	Other	Unit 1660 Press Buffered, Card Edg	Standard
Gas 9	*MFC Size	Cl2	Unit 1660 Press Buffered, Card Edg	Bypass w/ Purge
Gas 10	*MFC Size	NF3	Unit 1660 Press Buffered, Card Edg	Bypass w/ Purge
Gas 11				Bypass w/ Purge

	LFC Size	Liquid Name	LFC Type
Remote 1			
Remote 2			
Remote 3			

Chamber A Notes:

R0 DPS chamber, DTCU 0010-36930, source match 1110-01043, lower chamber wall 0020-33807, upper chamber 0240-37687, throttle 0010-36908

Chamber B Information

Chamber Type	Chamber Process	Susceptor /Pedestal	Process Kit Type
MkII		Electostatic Chuck	
Manometer Config	**Lid Type**	**Wall Cooling**	**Chamber Pump**
Single	Heated (Etch)		Alcatel
Manometer 1	**Throttle Valve**	**Heater / Cathode Cooling**	**Pump Configuration**
1 Torr	Butterfly		ADP 81
Manometer 2	**LF Generator**	**Endpoint System**	**Turbo Pump**
None	None	YES	Alcatel 5402CTS
Slit Valve O-Ring	**HF Generator**	**Enpoint Software Rev.**	**Heated Valve Stack**
	ENI 12B-02		NO
Chamber O-Rings	**RF Match**	**Chamber Clamps**	
	Phase 4 - Etch	NO	

Chamber B Gases:

	MFC Size	Gas Name	MFC Type	Gas Stick Configuration
Gas 1	*MFC Size	NF3	Unit 1660 Press Buffered, Card Edg	Bypass w/ Purge
Gas 2	*MFC Size	C4F8	Unit 1660 Press Buffered, Card Edg	Bypass w/ Purge
Gas 3	*MFC Size	SF6	Unit 1660 Press Buffered, Card Edg	Bypass w/ Purge
Gas 4				
Gas 5				
Gas 6				
Gas 7				
Gas 8				
Gas 9				
Gas 10				
Gas 11				
	LFC Size	**Liquid Name**	**LFC Type**	
Remote 1				
Remote 2				
Remote 3				

Chamber B Notes:

mark II 3 piece body, mxp magnets, mk II shields, 0010-09019 throttle, has an ESC cathode with HV module

Chamber C Information

Chamber Type	Chamber Process	Susceptor /Pedestal	Process Kit Type
Etch		Electostatic Chuck	
Manometer Config	**Lid Type**	**Wall Cooling**	**Chamber Pump**
Single	Heated (Etch)		Alcatel
Manometer 1	**Throttle Valve**	**Heater / Cathode Cooling**	**Pump Configuration**
1 Torr	Butterfly		ADP 81
Manometer 2	**LF Generator**	**Endpoint System**	**Turbo Pump**
	None	YES	Alcatel 5402CTS
Slit Valve O-Ring	**HF Generator**	**Enpoint Software Rev.**	**Heated Valve Stack**
	ENI 12B-02		NO
Chamber O-Rings	**RF Match**	**Chamber Clamps**	
	Phase 4 - Etch	NO	

Chamber C Gases:

	MFC Size	Gas Name	MFC Type	Gas Stick Configuration
Gas 1	*MFC Size	HeO2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 2	*MFC Size	N2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 3	*MFC Size	CHF3	Unit 1660 Press Buffered, Card Edg	Standard
Gas 4	*MFC Size	O2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 5	*MFC Size	Ar	Unit 1660 Press Buffered, Card Edg	Standard
Gas 6	*MFC Size	C4F8	Unit 1660 Press Buffered, Card Edg	Standard
Gas 7	100 sccm	CF4	Unit 1660 Press Buffered, Card Edg	Standard
Gas 8	25 sccm	O2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 9		Cl2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 10	100 sccm	NF3	Unit 1660 Press Buffered, Card Edg	Standard
Gas 11				

	LFC Size	Liquid Name	LFC Type
Remote 1			
Remote 2			
Remote 3			

Chamber C Notes:

Uni-body chamber wall, mxp magnets and shields, 0010-09019 throttle, has an ESC cathode with high volgate module 0010-09933

Chamber D Information

Chamber Type	Chamber Process	Susceptor /Pedestal	Process Kit Type
DPS	Trench	Electostatic Chuck	
Manometer Config	**Lid Type**	**Wall Cooling**	**Chamber Pump**
Dual	DPS deep trench		Edwards
Manometer 1	**Throttle Valve**	**Heater / Cathode Cooling**	**Pump Configuration**
.1 Torr	VAT THROTTLING GAT		Ih80
Manometer 2	**Source Generator**	**Endpoint System**	**Turbo Pump**
10 Torr	AE RF-20RWC	YES	ALCATEL ATH 1300
Slit Valve O-Ring	**Bias Generator**	**Enpoint Software Rev.**	**Heated Valve Stack**
	RFPP LF10		YES
Chamber O-Rings	**RF Match**	**Chamber Clamps**	
	ATL-100RA	NO	

Chamber D Gases:

	MFC Size	Gas Name	MFC Type	Gas Stick Configuration
Gas 1	*MFC Size	N2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 2	*MFC Size	BCl3	Unit 1660 Press Buffered, Card Edg	Standard
Gas 3	*MFC Size	CF4	Unit 1660 Press Buffered, Card Edg	Standard
Gas 4	*MFC Size	Cl2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 5	*MFC Size	Ar	Unit 1660 Press Buffered, Card Edg	Standard
Gas 6	*MFC Size	O2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 7	*MFC Size	NF3	Unit 1660 Press Buffered, Card Edg	Standard
Gas 8	*MFC Size	C4F8	Unit 1660 Press Buffered, Card Edg	Standard
Gas 9	*MFC Size	SF6	Unit 1660 Press Buffered, Card Edg	Standard
Gas 10	*MFC Size	H2	Unit 1660 Press Buffered, Card Edg	Standard
Gas 11				

	LFC Size	Liquid Name	LFC Type
Remote 1			
Remote 2			
Remote 3			

Chamber D Notes:

R1 DPS chamber, DTCU 0010-38754, source match 1110-01063, lower chamber body 0021-09625, upper chamber 0010-13830